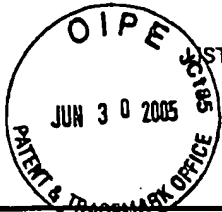



Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1518		SERIAL NO. 09/653,156	
				LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)			
				APPLICANT: Vishnu K. Agarwal et al.			
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Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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TN	AJ	KR 2002046433	05/2003	Lee, J.W.			
TN	AK	EP 1 508 906 A2	02/2005	Lee et al.			
	AL						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
TN	AM	Ritala et al.; <i>Perfectly Conformal TiN and Al2O3 Films Deposited by Atomic Layer Deposition</i> ; Chemical Vapor Deposition, v. 5, No. 1, 1999, pp. 7-9.
	AN	
	AO	

EXAMINER 	DATE CONSIDERED 8/30/05
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.